

MODEL **1061** Sem mill

A state-of-the-art ion milling and polishing system. It is compact, precise, and consistently produces high-quality scanning electron microscopy (SEM) samples in the shortest amount of time for a wide variety of applications.

Model 1061 SEM Mill specifications		
lon sources	Two TrueFocus ion sources	
	Variable energy (100 eV to 10.0 keV) operation	
	Beam current density up to 10 mA/cm ²	
	Milling angle range of 0 to +10°	
	Choice of single or dual ion source operation	
	Manual or motorized (optional) ion source angle adjustment	
	Independent ion source energy control	
	Adjustable spot size	
	Faraday cups for the direct measurement of beam current from each ion source; allows optimization and adjustment of the ion source parameters for specific applications	
Sample stage	Sample size:	
	 Cross section* Maximum: 10 x 10 x 4.0 mm [0.39 x 0.39 x 0.157 in.] Minimum: 3 x 3 x 0.7 mm [0.12 x 0.12 x 0.028 in.] 	
	 Planar 32 mm diameter x 25 mm height [1.25 x 1 in.] 	
	Automatic sample thickness sensing to establish the milling plane and maximize throughput	
	360° sample rotation with variable rotation speed	
	Sample rocking	
	Magnetic encoder provides absolute positioning accuracy	

* Standard size; other sizes available upon request.

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Cross-section station (optional)	Produces pristine cross-section samples	
	Allows precise positioning of the area of interest $$ – X, Y, and θ	
	Effective for use with a wide variety of materials, including semiconductor devices, multilayers, ceramics, and hard/brittle materials	
	Prepared region of interest is flat and free from damage for subsequent SEM imaging and analysis	
	Accommodates a wide range of sample and mask sizes:	
	 Sample and mask align both laterally and angularly 	
	 Multiple uses from a single mask 	
Sample cooling (optional)	Liquid nitrogen conductive cooling with integral dewar and automatic temperature interlocks	
	Dewar access positioned close to instrument operator	
	Ability to program and maintain a specific temperature between ambient and cryogenic	
	Choice of:	
	• Standard dewar capacity (3 to 5 hours of cryo conditions)	
	• Extended dewar capacity (18+ hours of cryo conditions)	
Automatic termination	Automatic termination by time or temperature	
Vacuum system	Turbomolecular drag pump and an oil-free, multi-stage diaphragm pump	
	Vacuum sensing with a cold cathode, full-range gauge	
Vacuum or inert gas transfer capsule (optional)	Allows transfer or storage of a sample at vacuum or in an inert gas environment	
Process gas	UHP argon (99.999%); nominal 15 psi delivery pressure required	
	Automatic gas control using two mass flow controllers	
User interface	Instrument operation controlled via 254 mm [10 in.], ergonomically adjustable touch screen	
	Stack light indicator for determining milling operations status from a distance (optional)	

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Model 1061 SEM Mill specificati	ons
Microscope (optional)	Load lock window accommodates the following microscopes:
	 7 to 45X stereo microscope attachment for direct specimen observation
	 525X high-magnification microscope and CMOS (complementary metal oxide semiconductor) camera system for site-specific image acquisition and display
	 1,960X high-magnification microscope and CMOS camera system for site-specific image acquisition and display
In situ viewing and imaging	Sample can be monitored in situ in the milling position when using either the stereo or the high-magnification microscope
	Viewing window protected by a programmable shutter that prevents buildup of sputtered material and preserves the ability to observe the sample in situ
Sample illumination	Both the high-magnification and stereo microscopes have light sources that provide top-down, user adjustable, reflected sample illumination
Enclosure	Width (includes room on either side for service access: 127 cm [50 in.]
	Height:
	 Minimum height (without microscope or stack light options): 61 cm [32 in.]
	 Maximum height (with stack light option): 77 cm [38 in.]
	Depth (includes room for service access and exhaust fan air flow): 102 cm [40 in.]
	Enclosure design offers easy access to internal components when performing maintenance tasks
Weight	73 kg [161 lb.]
Power	100/120/220/240 VAC, 50/60 Hz, 720 W
Warranty	One year
Service contracts	Contact <u>sales@fischione.com</u>



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